

**AMENDMENTS TO THE CLAIMS**

This listing of claims will replace all prior versions and listings of claims in the application:

**LISTING OF CLAIMS:**

A1 1. (Currently Amended) An apparatus for film deposition equipped with a vacuum chamber capable of maintaining vacuum therein, in which a film is deposited on surfaces of a substrate, which comprises ~~traveling means for~~ a traveler which vertically ~~traveling~~ travels a continuous sheet as the substrate; and a pair of film ~~deposition means for~~ depositors which continuously ~~depositing~~ deposit the film on the surfaces of the continuous sheet; said film ~~deposition means~~ depositors being vertically arranged and horizontally ~~faced~~ facing each other, and ~~said the~~ the continuous sheet being traveled between a pair of ~~the said film deposition means~~ depositors.

2. (Currently Amended) The apparatus according to claim 1, wherein ~~film deposition sources in said film deposition means are~~ depositors comprise a pair of magnetron sputtering cathodes.

3. (Currently Amended) ~~The apparatus~~ A system comprising the apparatus according to claim 1, wherein ~~said the~~ continuous sheet is at least one selected from the group consisting of a web, a knit and a non-woven fabric, each formed of organic fibers.

4. (Currently Amended) ~~The apparatus~~ system according to claim 3, wherein ~~said the~~ continuous sheet is a non-woven fabric having a mass of 5 to 300g/m<sup>2</sup>.

5. (Original) The apparatus according to claim 2, wherein a target material for said cathodes is cobalt, copper, zinc, titanium, silver, tin, or an alloy thereof.

6. (Currently Amended) The apparatus according to claim 1, wherein a gas is used for said film deposition, and the gas is an inert gas, or a gas mixture of the inert gas and one or more kinds selected from the group consisting of oxygen-containing gas, nitrogen-containing gas and ~~carbon gas containing~~ carbon-containing gas.

7. (Currently Amended) The apparatus according to claim 3, wherein the continuous sheet is a non-woven fabric having a mass of 40g/m<sup>2</sup> ~~is used as said continuous sheet, and~~ a tension applied thereto is in the range of 1 to 15N/m.

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8. (Currently Amended) A process for film deposition in which a film is deposited on surfaces of a substrate in a vacuum chamber capable of maintaining a vacuum therein, which comprises ~~the steps of~~ vertically traveling a continuous sheet as a substrate; and continuously conducting a film deposition on ~~the~~ surfaces of the continuous sheet; the film deposition being conducted horizontally on the surfaces of the vertically traveling continuous sheet by film depositors vertically arranged and horizontally facing each other.

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9. (New) The process according to claim 8, wherein the sheet is at least one selected from the group consisting of a web, a knit and a non-woven fabric, each formed of organic fibers.

10. (New) The process according to claim 8, wherein the continuous sheet is a non-woven fabric having a mass of 5 to 300g/m<sup>2</sup>.

11. (New) The process according to claim 8, wherein the film depositors comprise cathodes, and the film deposition is carried out using a target material for the cathodes, wherein the target material is cobalt, copper, zinc, titanium, silver, tin, or an alloy thereof.

12. (New) The process according to claim 8, comprising using a gas for the film deposition, wherein the gas is an inert gas, or a gas mixture of the inert gas and one or more kinds selected from the group consisting of oxygen-containing gas, nitrogen-containing gas and carbon-containing gas.

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13. (New) The apparatus according to claim 1, comprising pretreatment electrodes provided upstream of said fiber depositors.

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